

Fig. 1

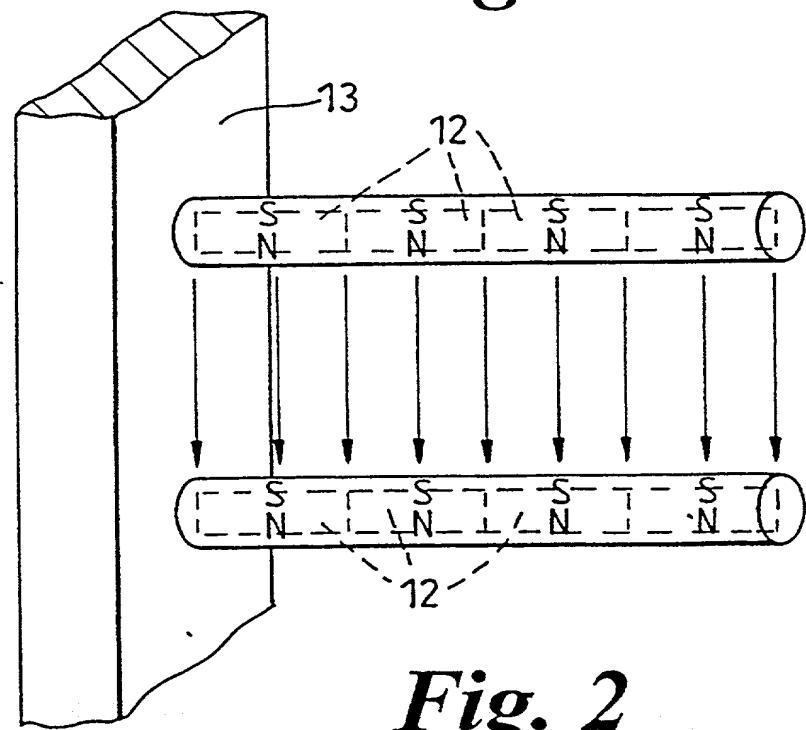


Fig. 2

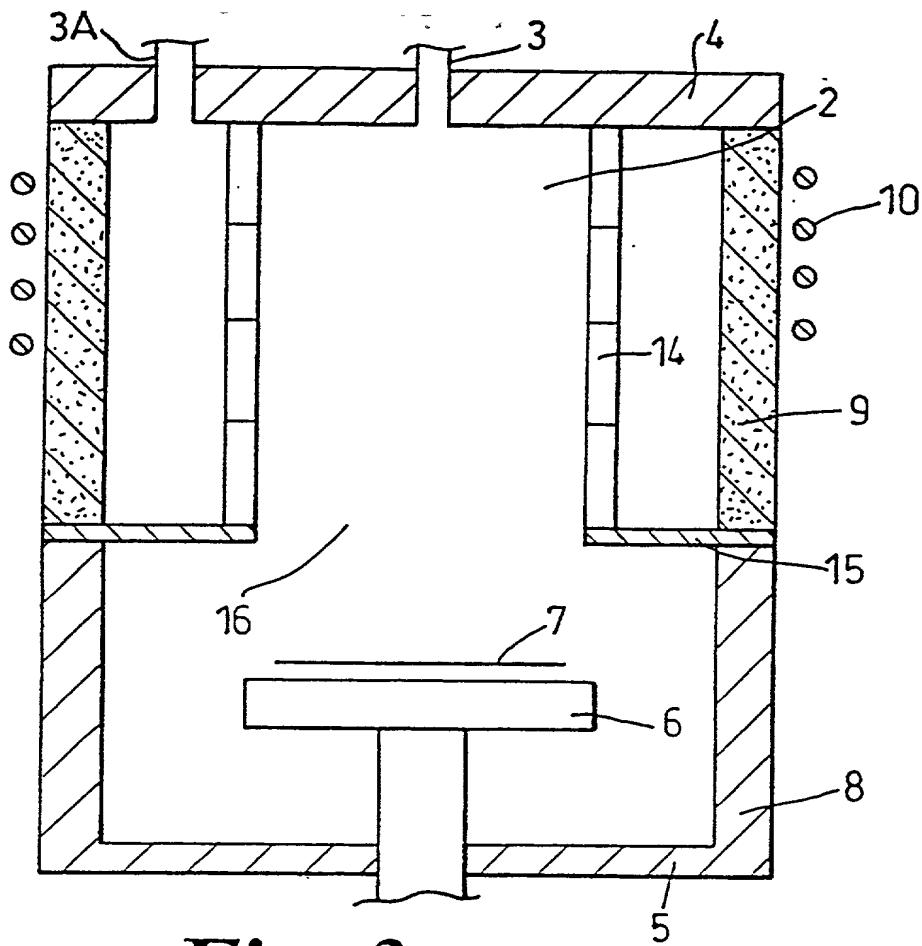


Fig. 3

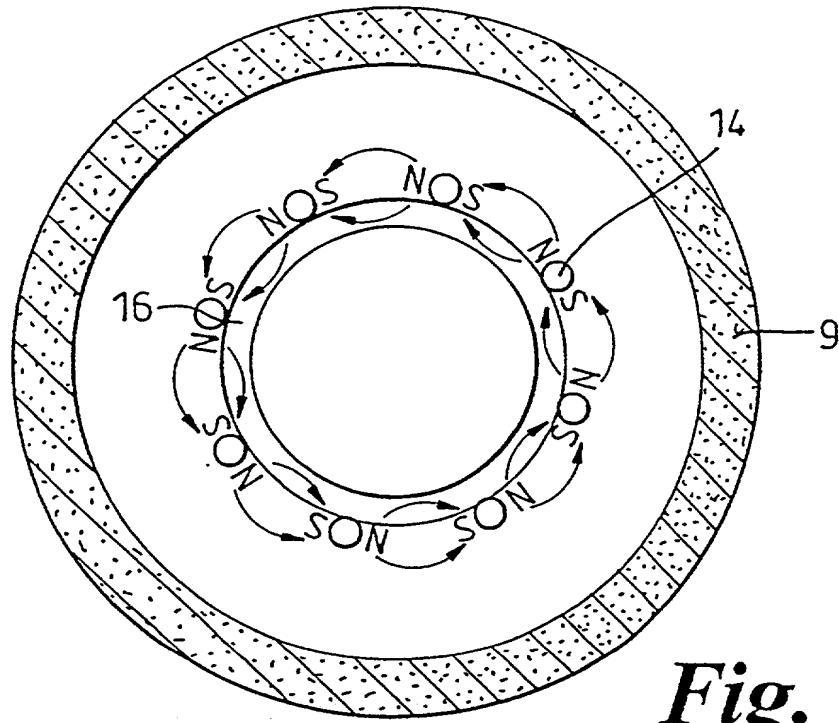


Fig. 4

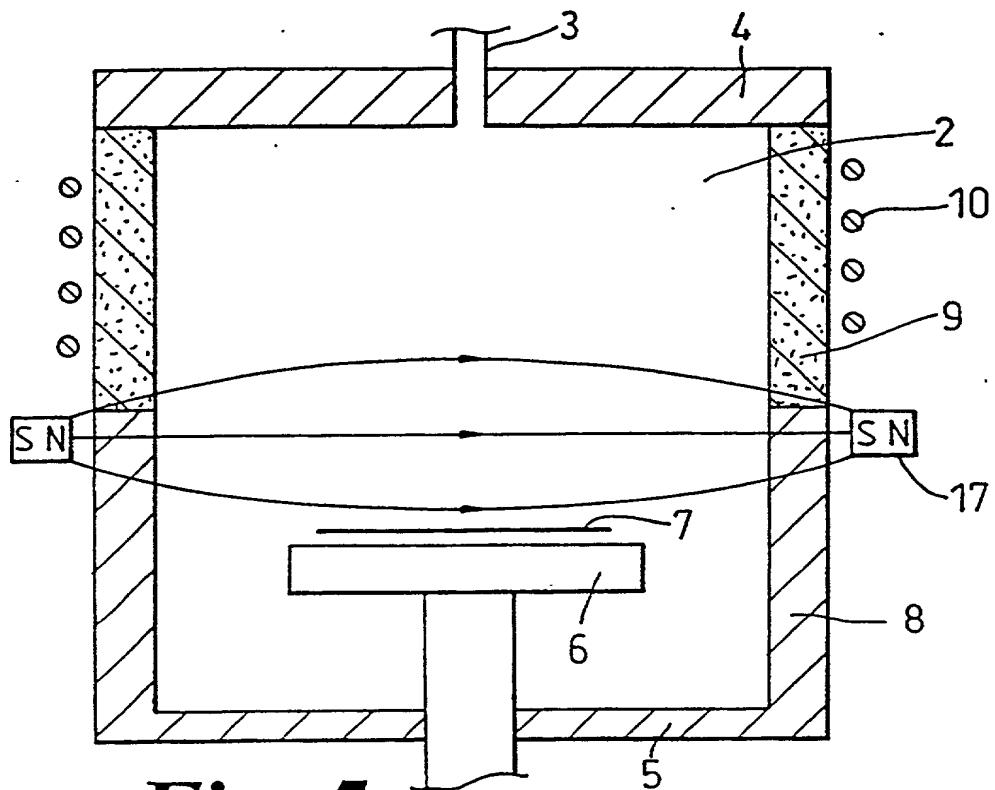


Fig. 5.

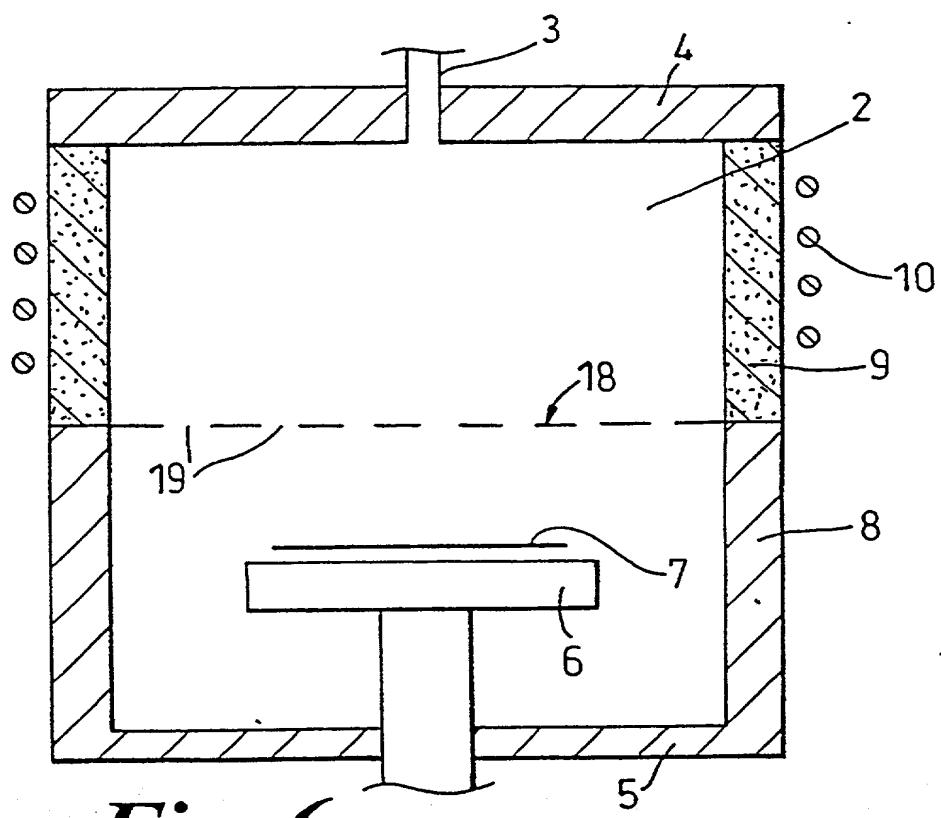


Fig. 6

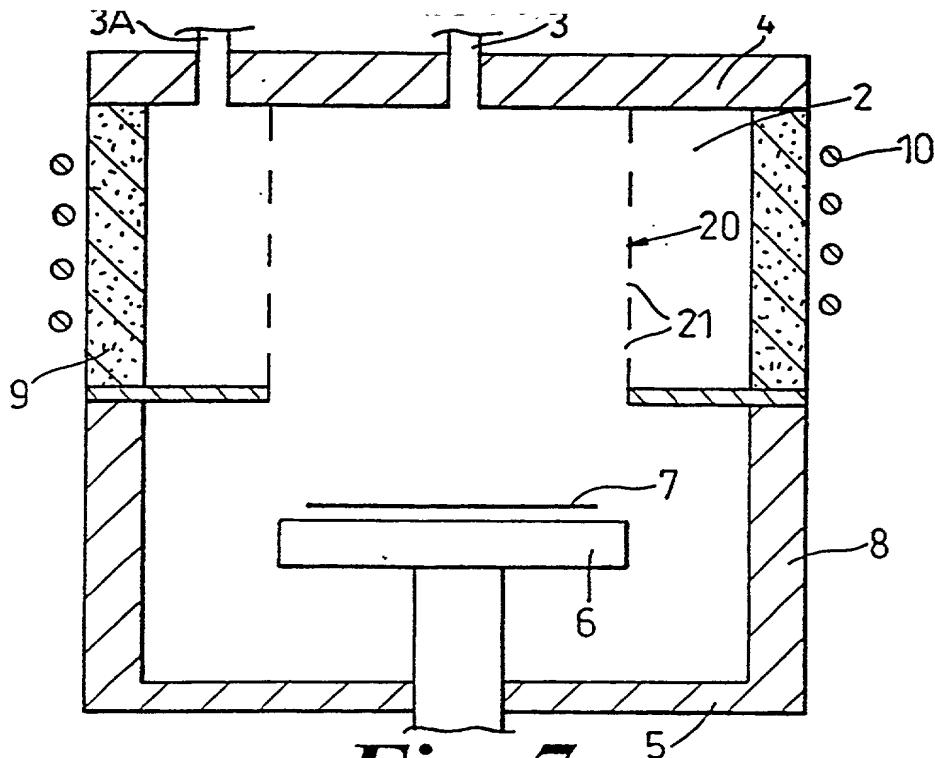


Fig. 7

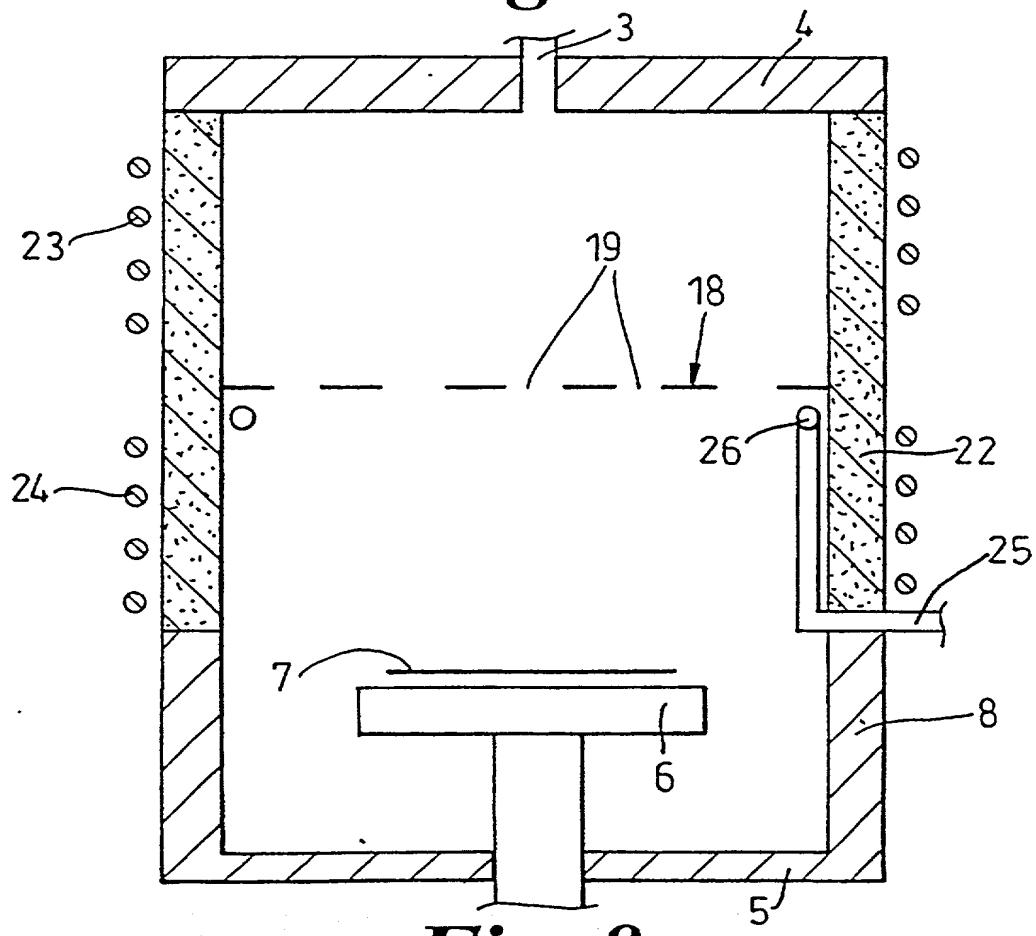


Fig. 8

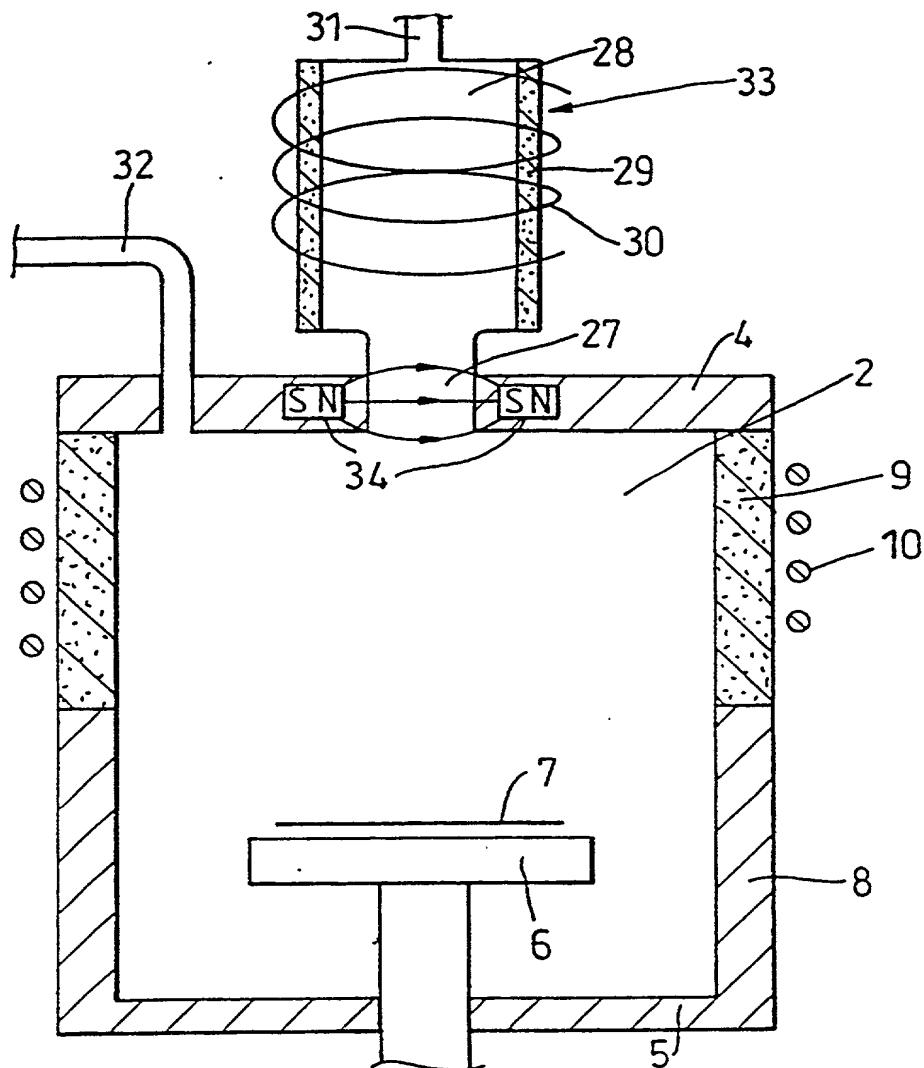


Fig. 9

PULSED SOURCE

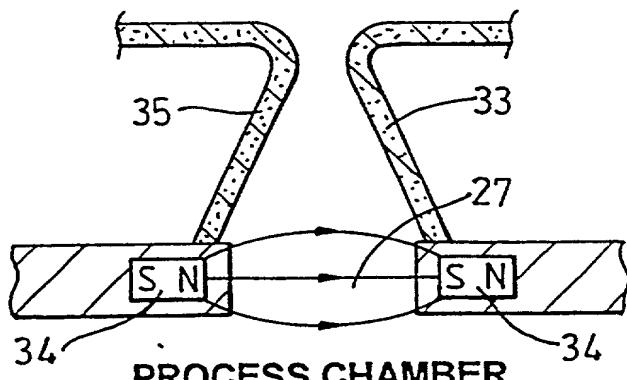


Fig. 10

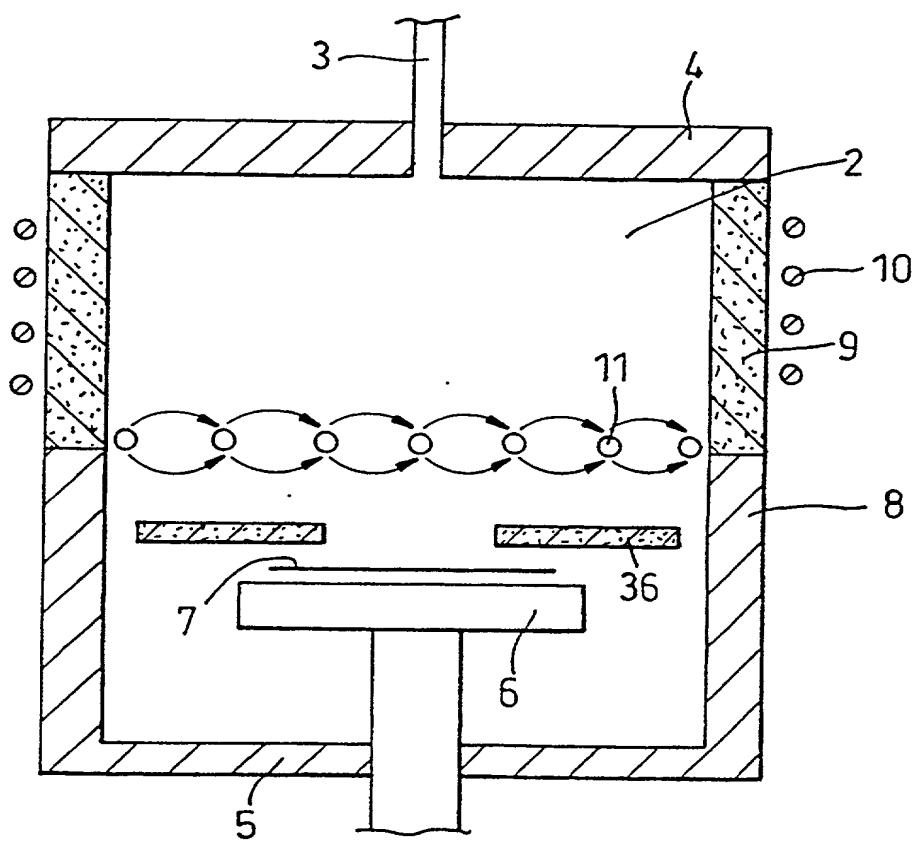


Fig. 11

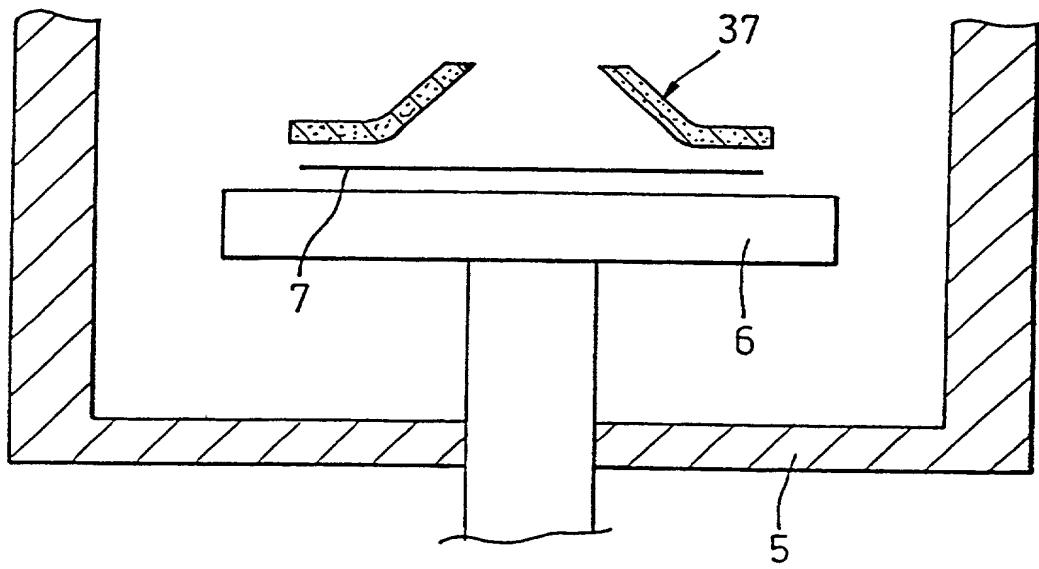


Fig. 12A

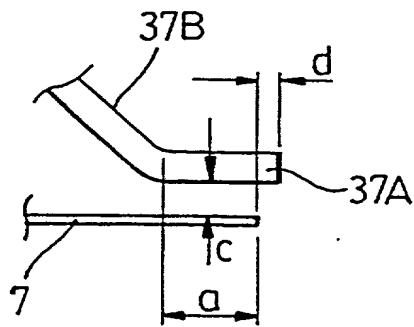


Fig. 12B

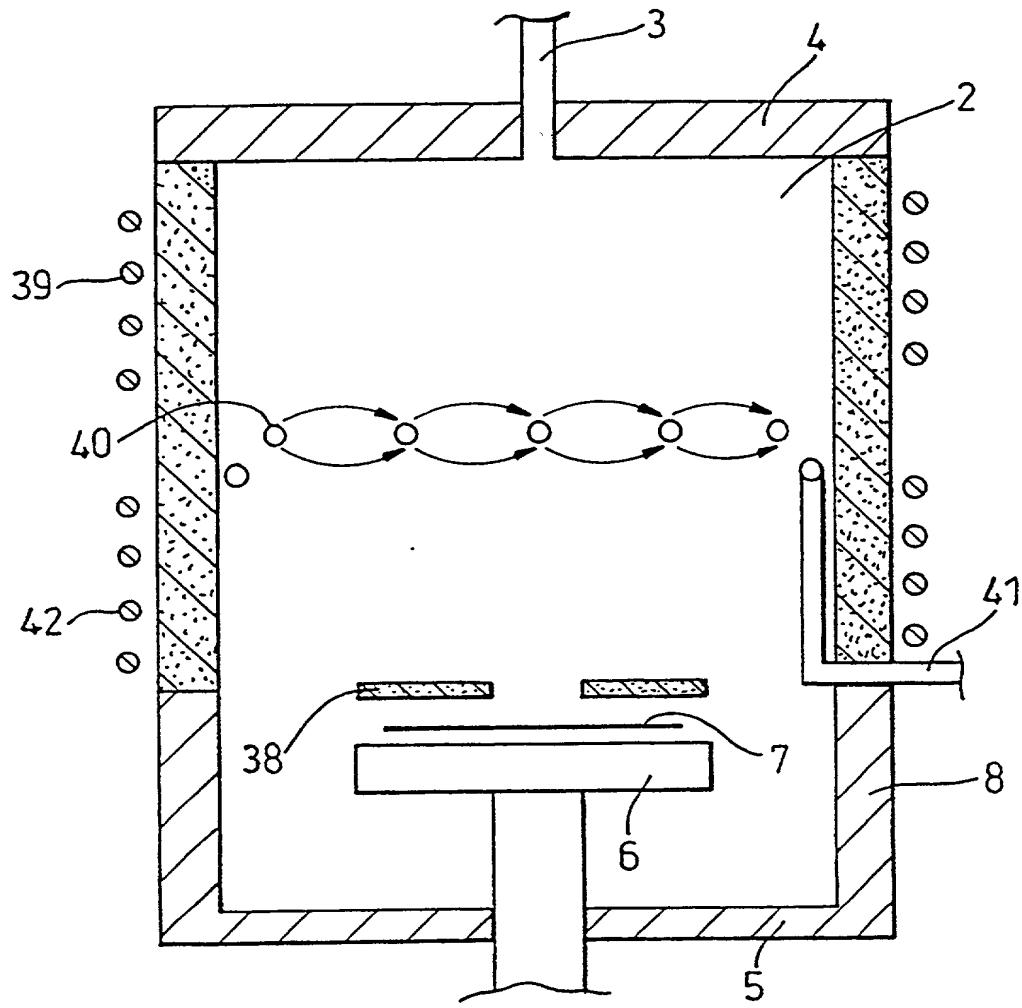


Fig. 13

EFFECT OF MAGNETIC ATTENUATOR

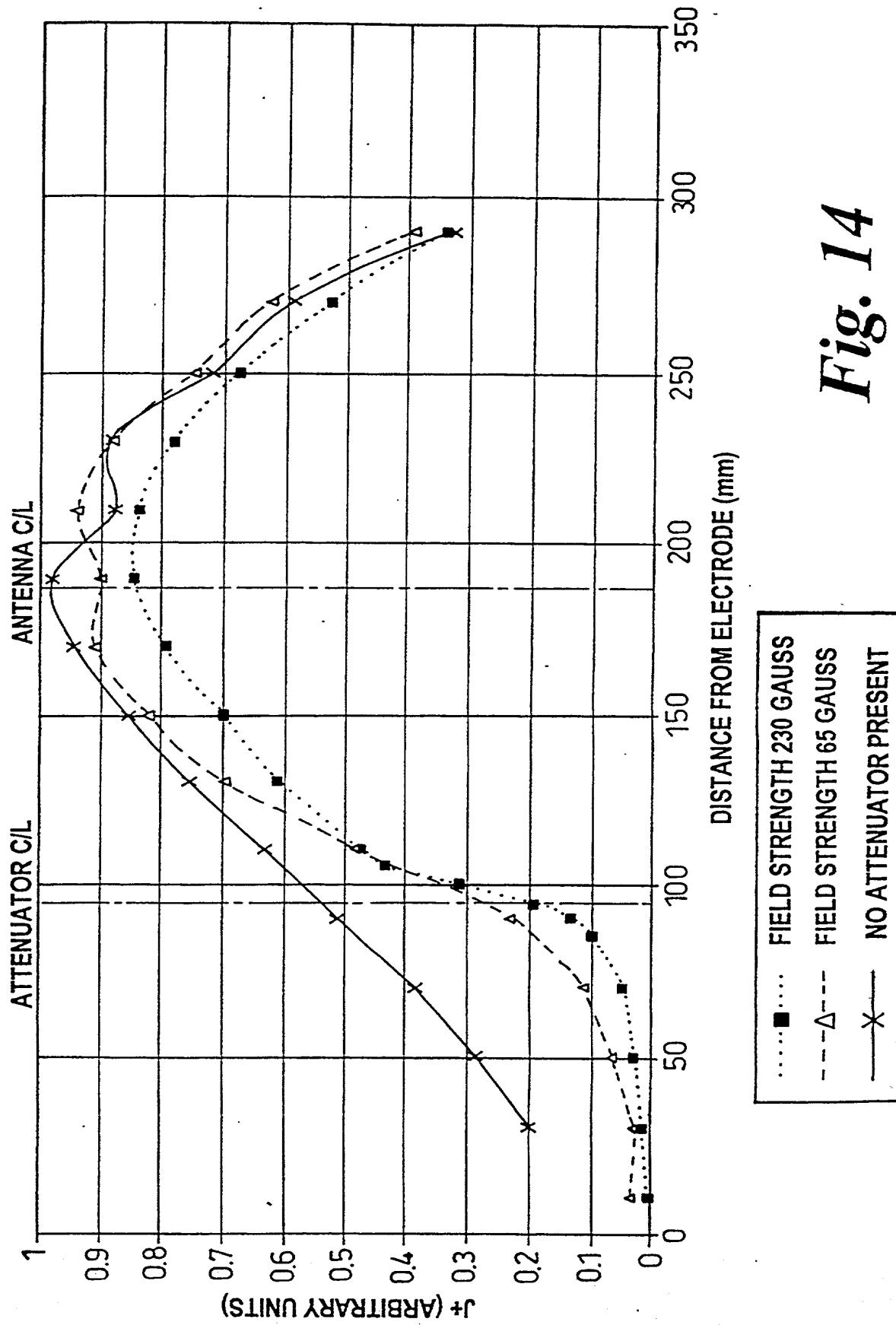
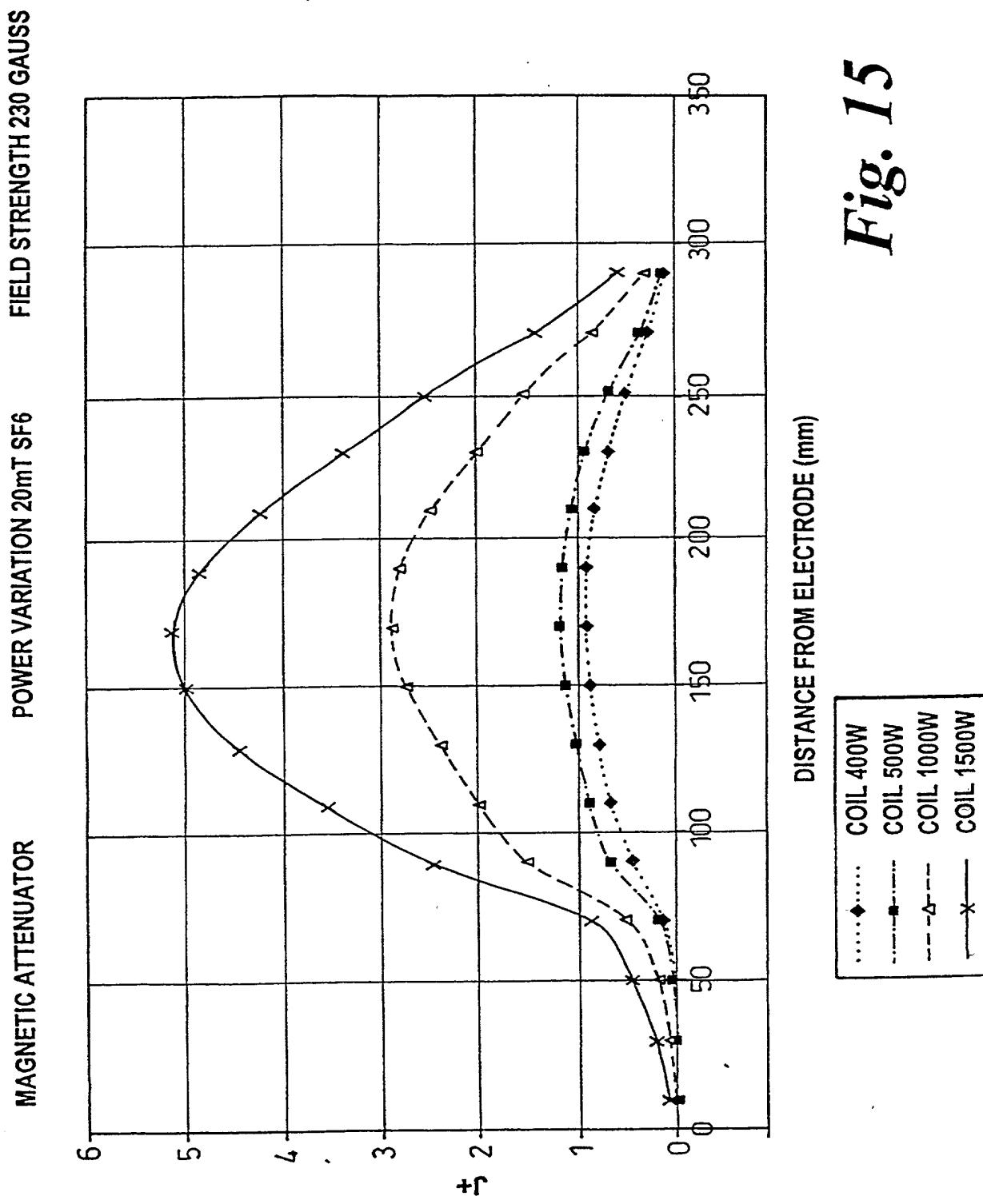


Fig. 14

Fig. 15



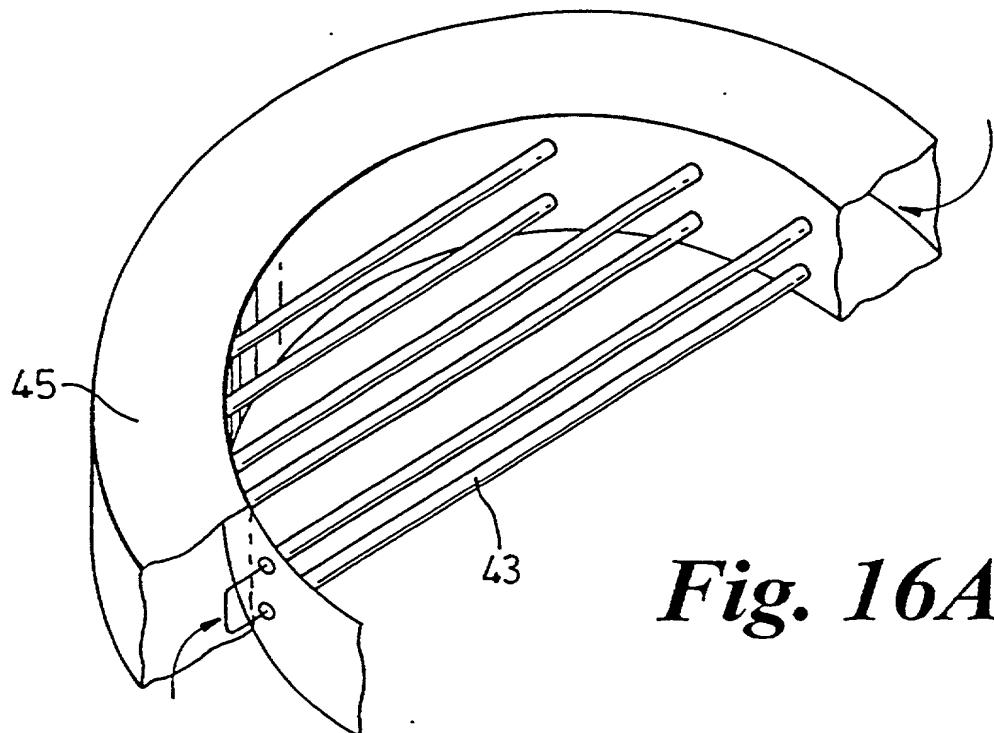


Fig. 16A

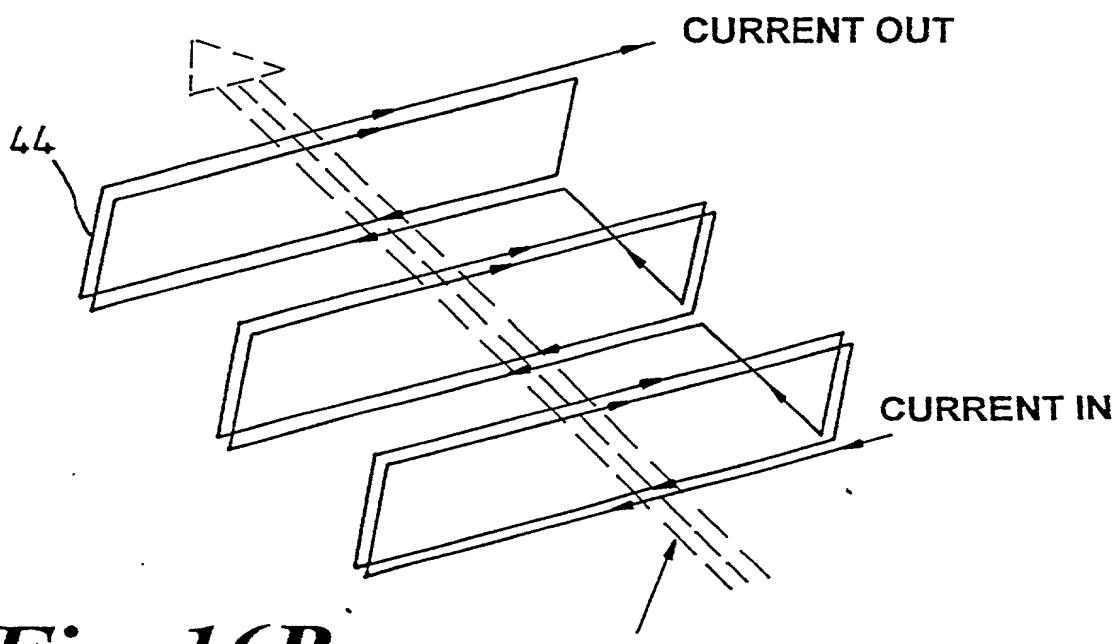
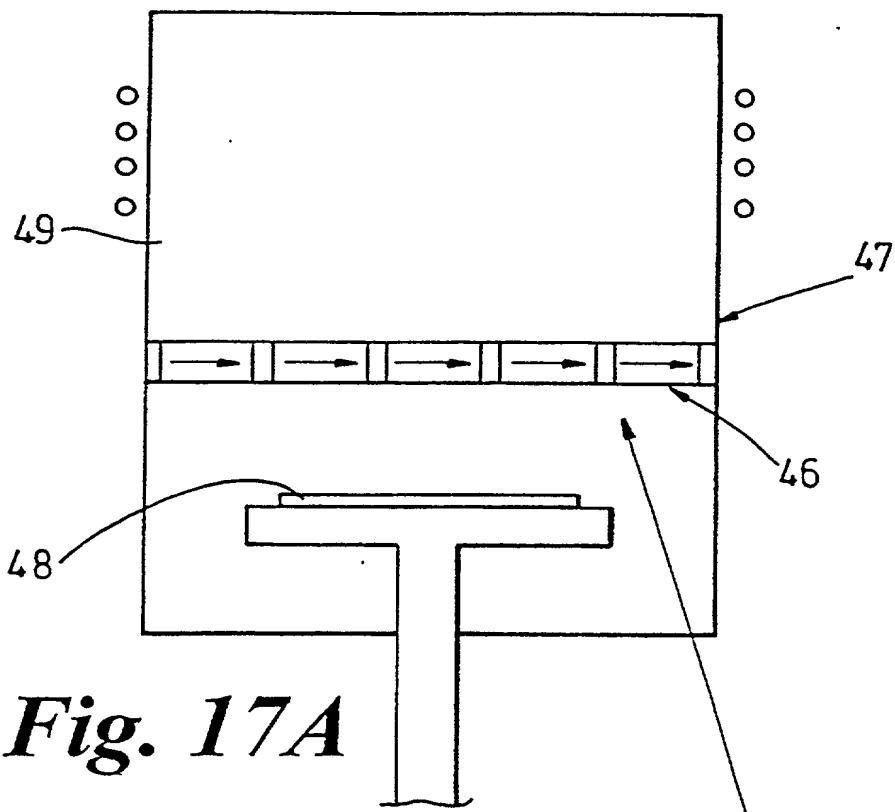


Fig. 16B



VIEW FIG.17B

FIELD

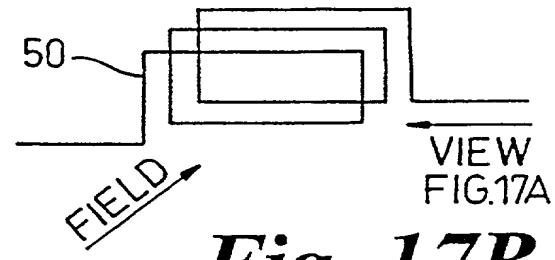


Fig. 17B

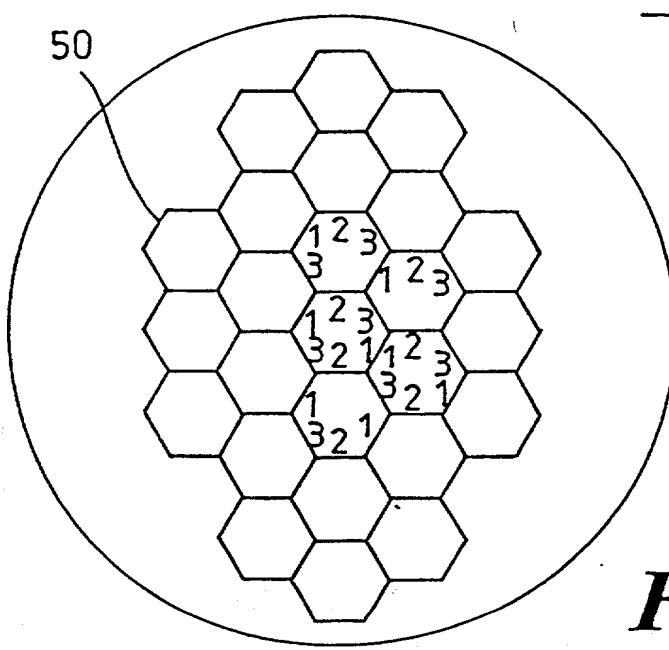


Fig. 17C

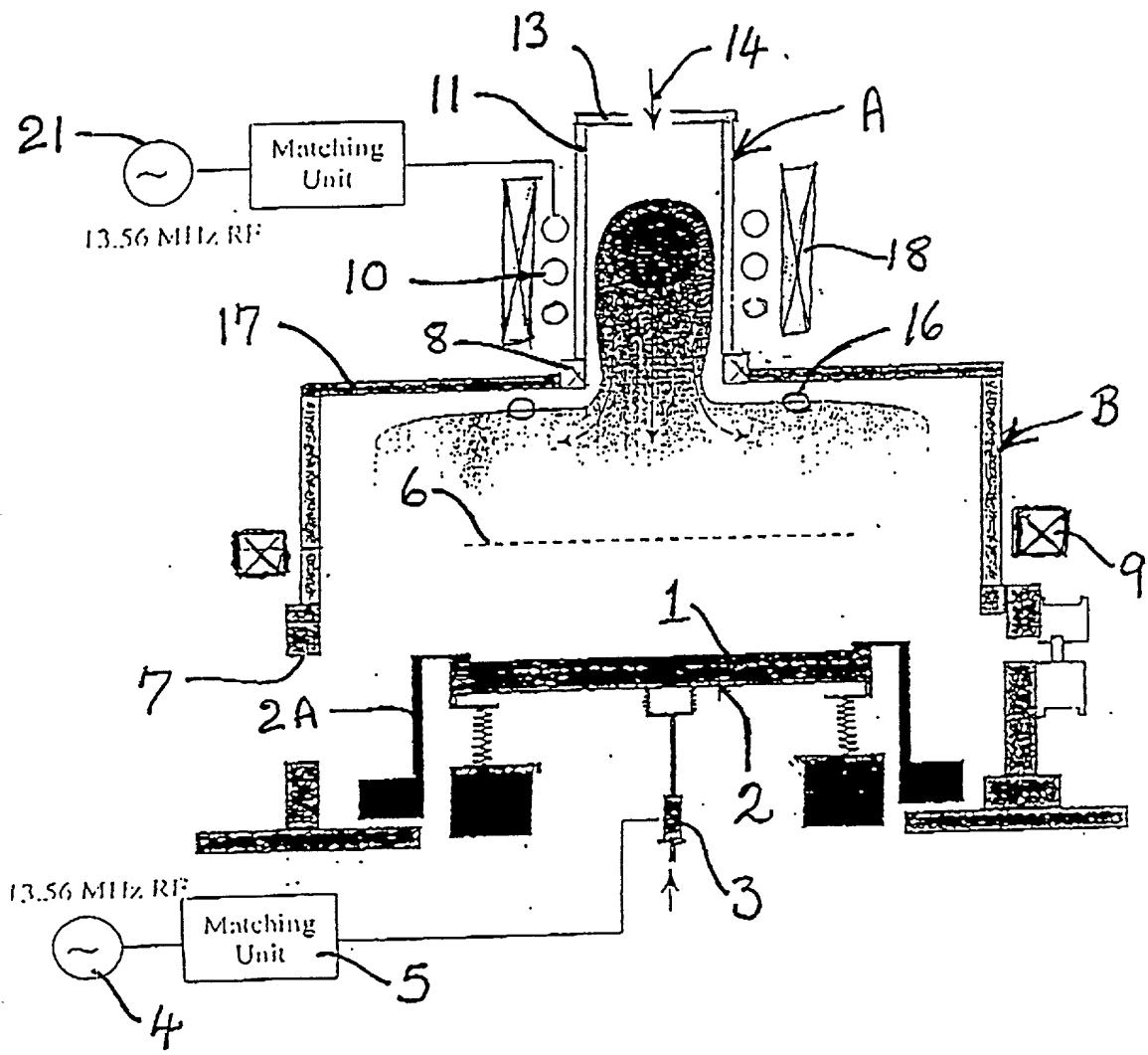


Fig. 18

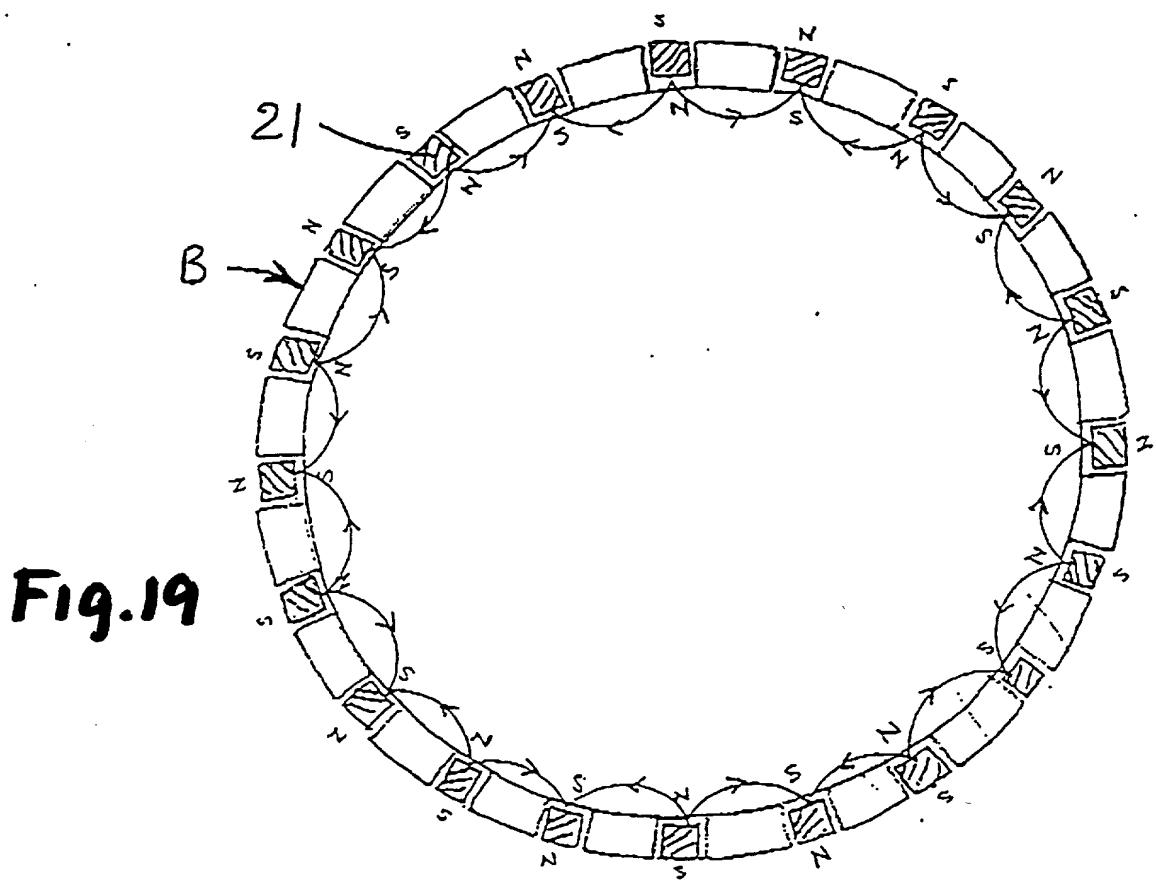


Fig. 19

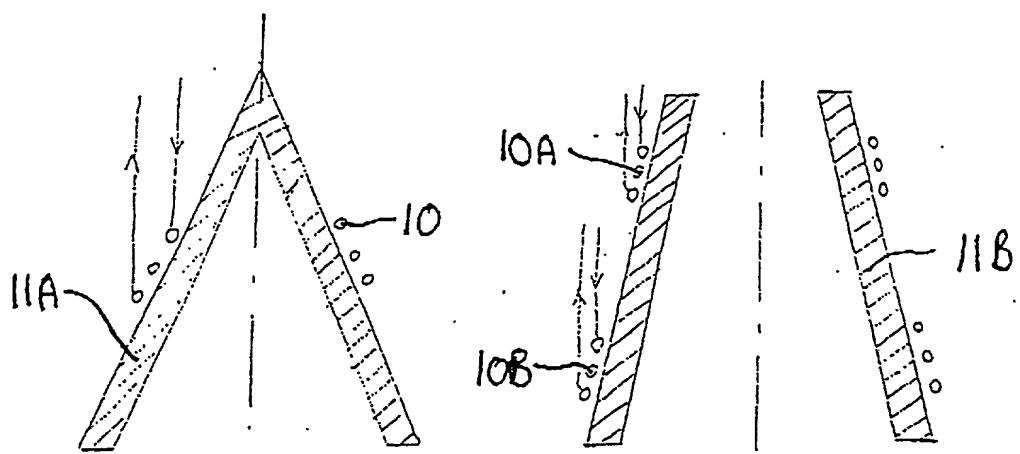


FIG. 20A

FIG. 20B

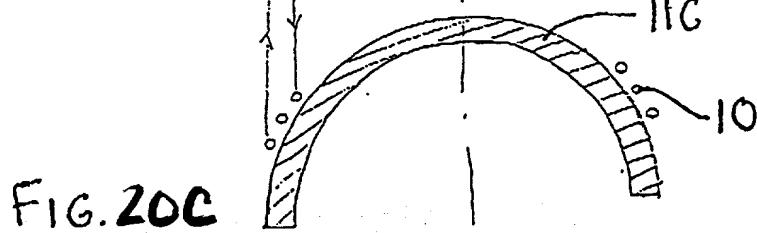


FIG. 20C

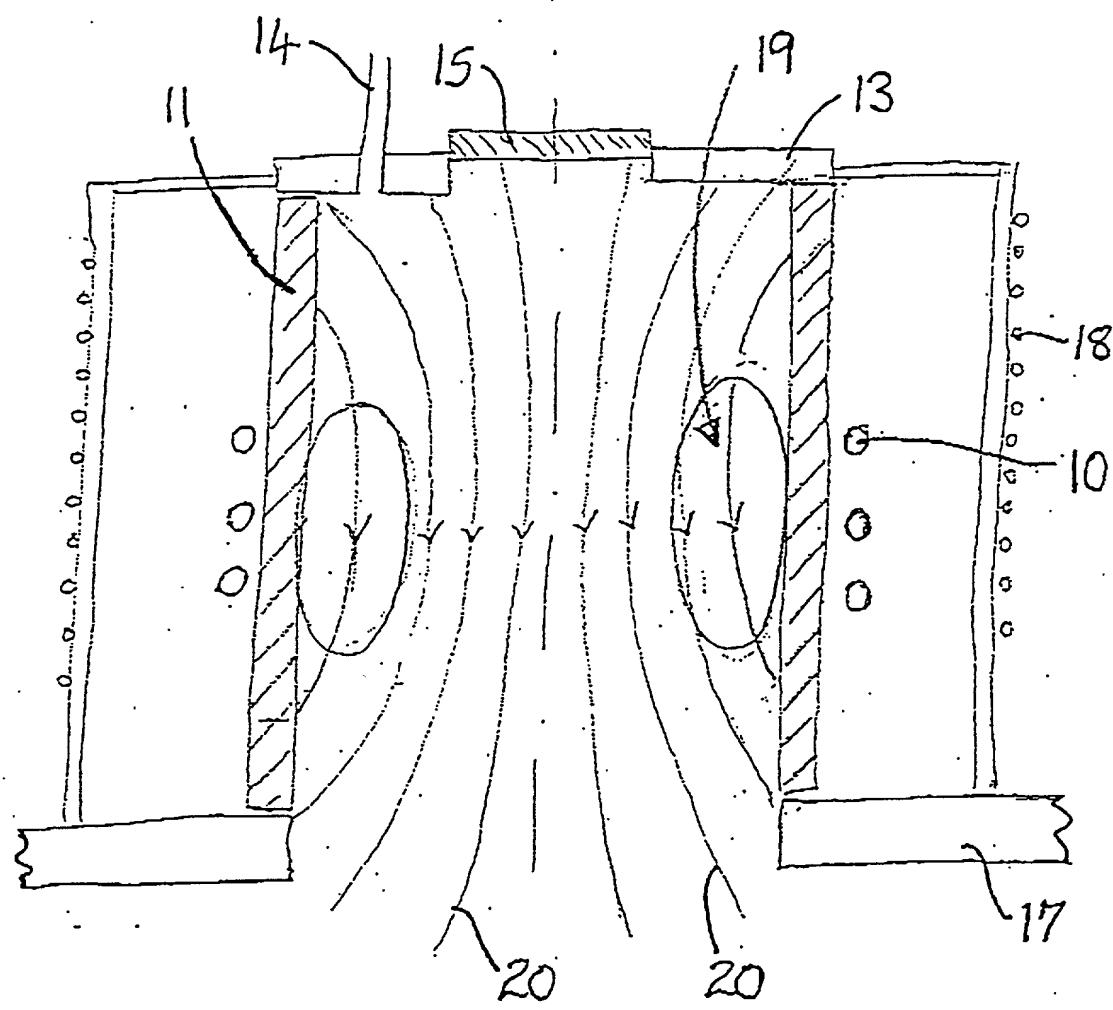


FIG. 21

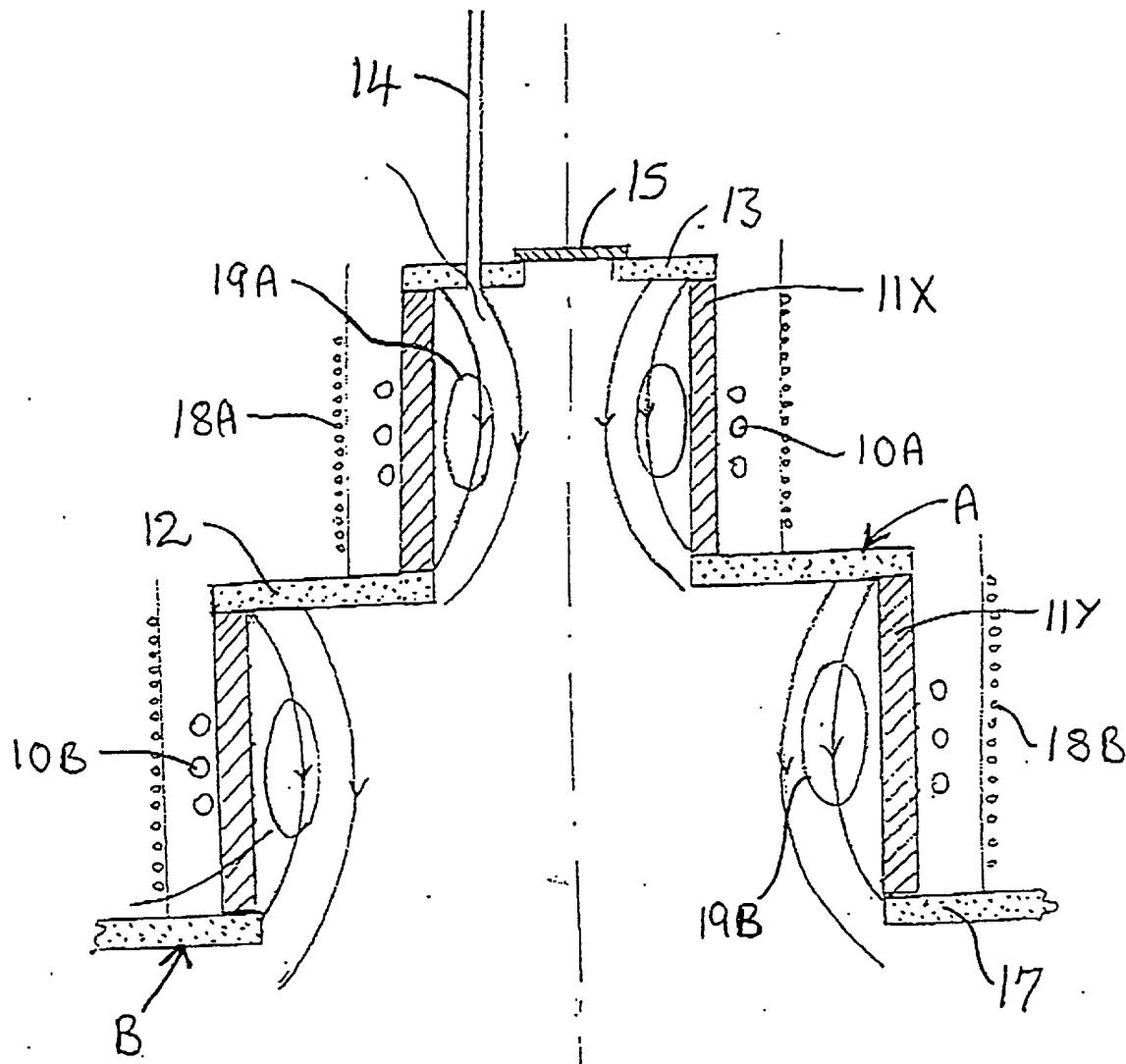


FIG. 22

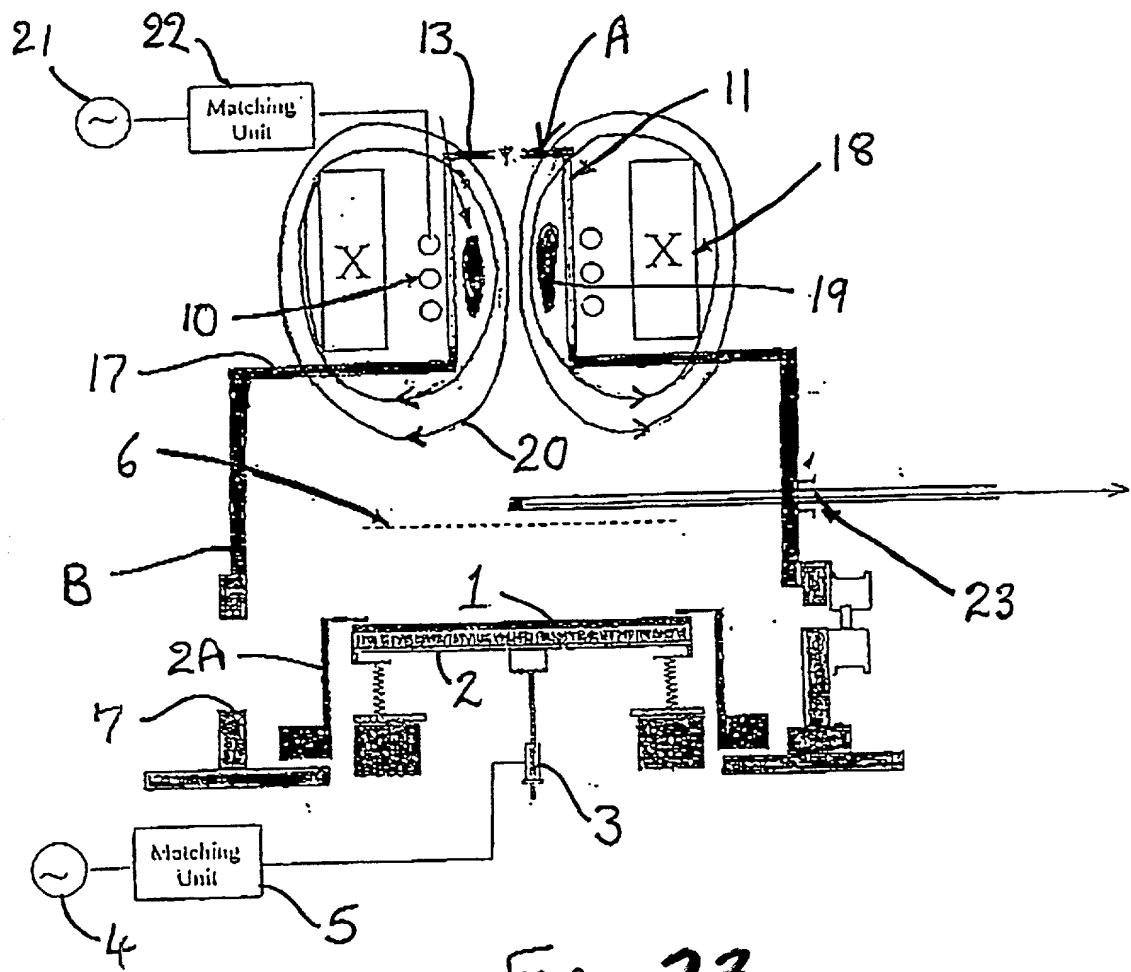


FIG. 23

Results from Langmuir probe. Constant gas flow, pressure, RF power into plasma

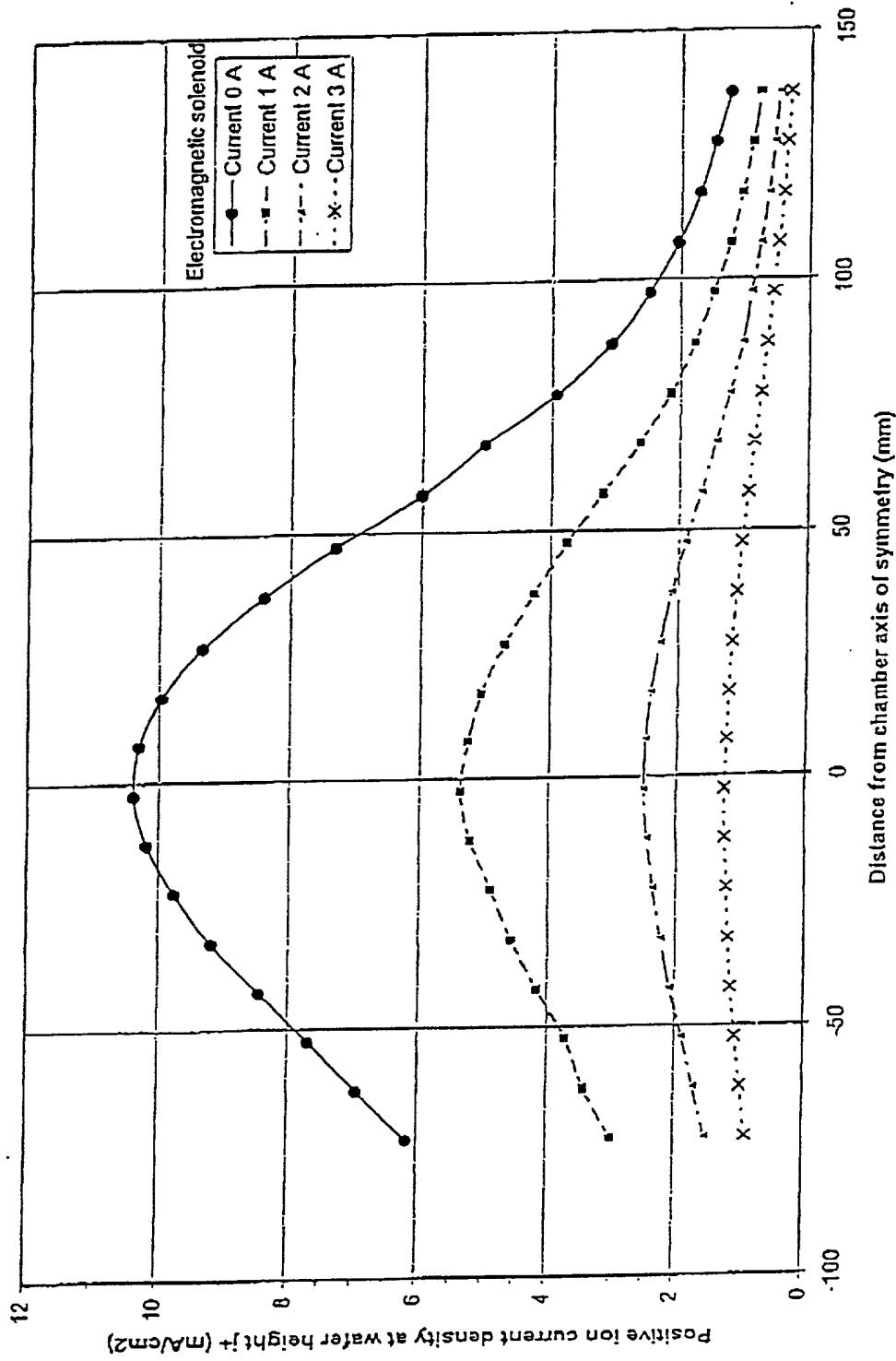


FIG. 24

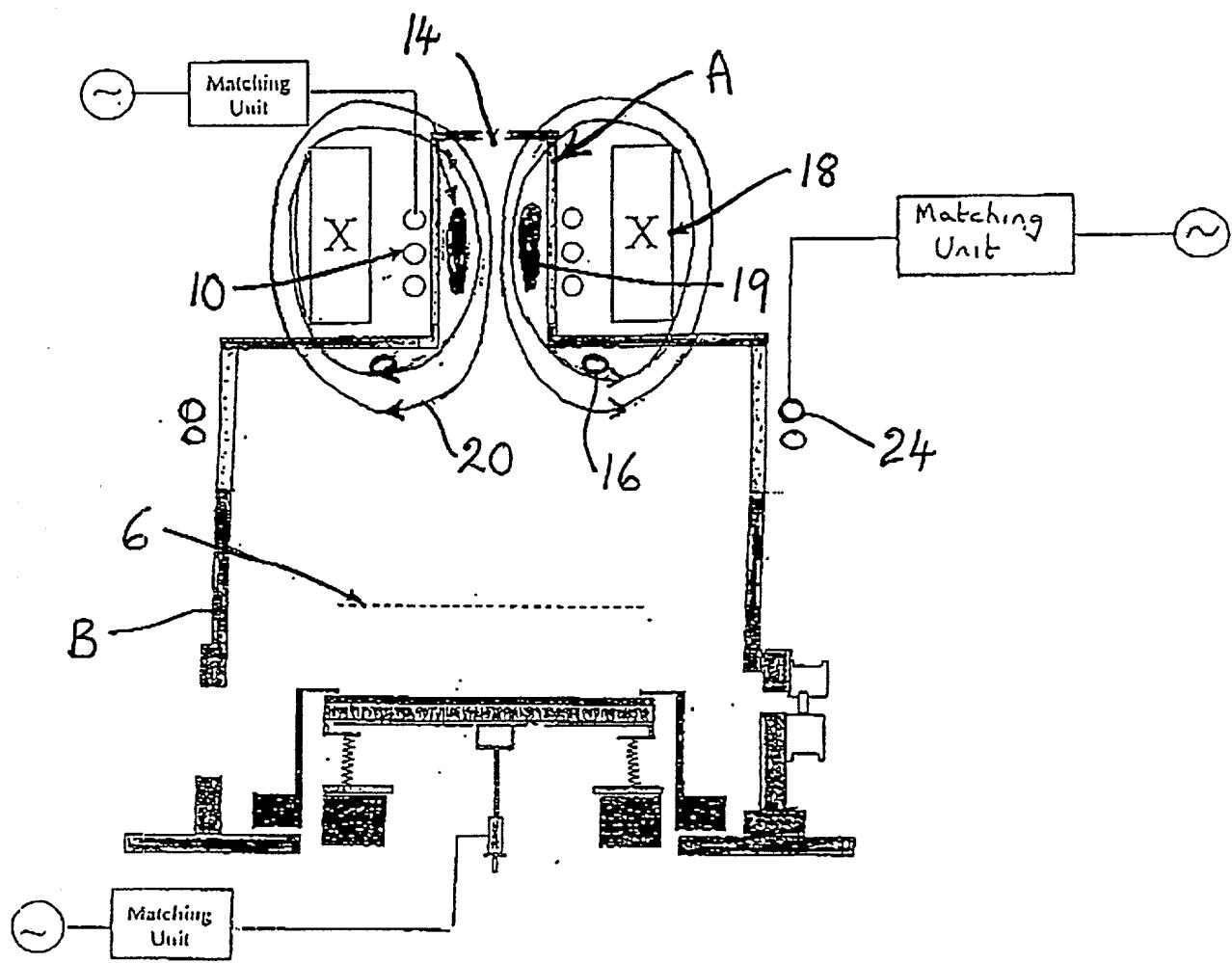


FIG. 25

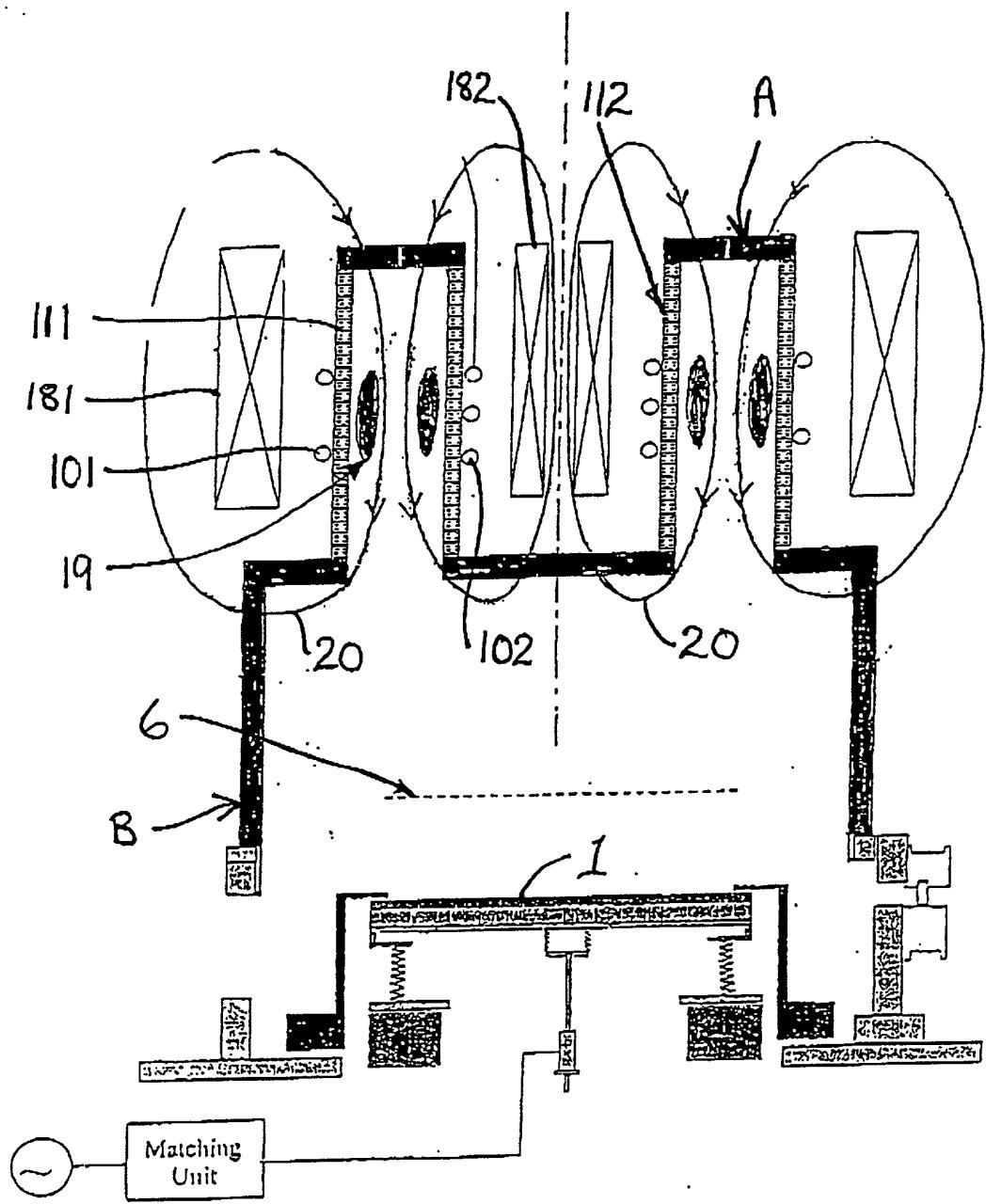


FIG. 26